

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Trung T. Doan

Serial No.:

Filed: August 31, 2000

For: CHEMICAL DISPENSING SYSTEM FOR
SEMICONDUCTOR WAFER PROCESSING

§ Group Art Unit:
§ Examiner:
§ Atty. Docket: 93-0421.05
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J/A
C.T.
10/27/00

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents

Washington, D.C. 20231

Dear Sir:

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Trung T. Doan
Signature

After awarding the above-captioned application the benefit of the priority date of its great
grandparent -- application #08/618,072, filed February 27, 1996 -- please amend the current
application as follows.

IN THE SPECIFICATION:

Immediately after the title, please add the following:

Related Applications

A1 This application is a divisional of pending U.S. Application Ser. No. 09/133,989, filed
Aug. 14, 1998; which is a continuation of U.S. Application Ser. No. 08/944,135, filed on Oct. 6,
1997 and issued as U.S. Patent No. 5,952,050; which is a continuation of U.S. Application Ser.
No. 08/618,072, filed Feb. 27, 1996 and now abandoned.